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01/28/02



U.S. UTILITY Patent Application

PATENT NUMBER and
ISSUE DATE

APPL NUM 10058614	FILING DATE 01/28/2002	CLASS 324	SUBCLASS 751	GAU 2602	EXAMINER NGUYEN, VINH P.
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**APPLICANTS: Han Liqun; McCord Mark; 2829

**CONTINUING DATA VERIFIED:
THIS APPLN CLAIMS BENEFIT OF 60/341,348 12/17/2001

** FOREIGN APPLICATIONS VERIFIED:

<input checked="" type="checkbox"/> A-PUB	<input type="checkbox"/> DO NOT PUBLISH	<input type="checkbox"/> RESCIND	
Priority claimed		<input type="checkbox"/> yes <input checked="" type="checkbox"/> no	ATTORNEY DOCKET NO:
35 USC 119 conditions met		<input type="checkbox"/> yes <input checked="" type="checkbox"/> no	KLA1P058
Verified and Acknowledged: Examiner's initials			
TITLE : Multiple electron beam inspection system using uniform focus and deflection			
U.S. DEPT. OF COMM./PAT. & TM-PTD-1301(P-1) 12-12			

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Assistant Examiner	
ISSUE FEE		Total Claims	Print Claim for O.G
Amount Due	Date Paid		
TERMINAL DISCLAIMER		DRAWING	
		Sheets Drawn	Figs. Drawn
		Print Fig.	
		Primary Examiner	
		Application Examiner	
PREPARED FOR ISSUE			
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